

Applicant: M. Kawaguchi  
U.S.S.N.: 09/470,615  
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Please amend the subject application as follows:

IN THE CLAIMS

**Amend** claim 1 to read as follows:

1. (TWICE AMENDED) A mechanism for supporting a substrate to be coated with the film, which mechanism is used in a film forming apparatus, comprising:  
*90*  
a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;  
*B1*  
a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;  
a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage and so as to support one end surface of the substrate, where said one end surface is the surface which faces downwards when the stage is angularly displaced to the film forming position; and  
moving means for moving the support members.

**Add** new claim(s) 17 that read(s) as follows:

17. (ADDED) A mechanism for supporting a substrate to be coated with the film, which mechanism is used in a film forming apparatus, comprising:  
*B2*  
a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;  
*S13*

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a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;

a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage and to support an end surface of the substrate, which faces downwards when the stage is angularly displaced to the film forming position;

*S03*  
moving means for moving the support members; and  
wherein the moving means is configured and arranged so as to cause the support members to one of:

- B2*  
*cont*
- (a) move in one direction with respect to a long axis of the support members,
  - (b) move in a direction generally perpendicular to a long axis of the support members,
  - (c) move in a direction generally perpendicular to the substrate end surface, or
  - (d) rotate about a long axis of each support member.

REMARKS

Applicant appreciates the Examiner's thorough examination of the subject application and requests reconsideration of the subject application based on the following remarks.